

Substitute for form 1449A/PTO			<b>Complete if Known</b>		
<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  (use as many sheets as necessary)			Application Number	10/828,486	
			Filing Date	4/19/2004	
			First Named Inventor	Anderson, Robert L.	
			Art Unit	2812	
			Examiner Name	GHYKA	
Sheet	1	of		Attorney Docket Number	019930-003710US

U.S. PATENT DOCUMENTS+					
Examiner Initials*	Cite No. <sup>1</sup>	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number Kind Code <sup>2</sup> (if known)			
AC	AA	US-5,212,582	05/18/1993	Nelson	
	AB	US-5,600,383	02/04/1997	Hombeck	
	AC	US-5,960,133	09/28/1999	Tomlinson	
	AD	US-6,028,689	02/22/2000	Michalick et al.	
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	AF	US-6,128,122	10/03/2000	Drake et al.	
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	BP	US-2003/0173112 A1	09-18-2003	Barnes et al.	
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	BU	US-			

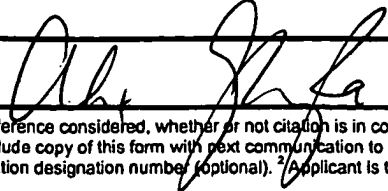
FOREIGN PATENT DOCUMENTS								
Examiner Initials*	Cite No. <sup>1</sup>	Foreign Patent Document			Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T <sup>4</sup>
		Country Code <sup>3</sup>	Number <sup>4</sup>	Kind Code <sup>5</sup> (if known)				
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NON PATENT LITERATURE DOCUMENTS			
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AL	CC	AKIYAMA, TERUNOBU et al., Controlled Stepwise Motion in Polysilicon Microstructures, Journal of Microelectromechanical Systems, Vol. 2, No. 1, September 1993, pp 106-110	
	CD	ASHRUF, C.M.A. et al., Galvanic Porous Silicon Formation Without External Contracts, Elsevier Science S.A., Sensors and Actuators 74 (1999), pp. 118-122.	
	CE	BEAN, KENNETH E., Anisotropic Etching of Silicon, IEEE Transactions on Electron Devices, Vol. ED-25, No. 10, October 1978, pp 1185-1193.	
	CF	CIARLO, Dino R., A Latching Accelerometer Fabricated by the Anisotropic Etching of (110) Oriented Silicon Wafers, 0860-1317/92/010010+04104.50, March 1992 IOP Publishing Ltd.	
	CG	DEWA, Andrew S., et al., Development of a Silicon Two-Axis Micromirror for an Optical Cross-Connect, Solid-State Sensor and Actuator Workshop, Hilton Head Island, South Carolina, June 4-6, 2000, pp. 93-96.	
	CH	FORD, JOSEPH E. et al., Wavelength Add-Drop Switching Using Tilted Micromirrors, Journal of Lightwave Technology, Vol. 17, No. 5, May 1999, pp. 904-911	
	CI	GRADE, John D., et al., A Large-Deflection Electrostatic Actuator for Optical Switching Applications, Solid-State Sensor and Actuator Workshop, Hilton Head Island, South Carolina, June 4-6, 2000, pp. 97-100	
	CJ	HOPKINS, Robert E., Some Thoughts on Lens Mounting, Optical Engineering, Vol. 15, No. 5, September-October 1976, pp. 428-430.	
	CK	KAAJAKARI, VILLE, et al., Ultrasonic Actuation for MEMS Dormancy-Related Stiction Reduction, In MEMS Reliability for Critical Applications, Proceedings of SPIE Vol. 4180, 2000, pp. 60-65.	
	CL	KOCH, T.L. et al., Anisotropically Etched Deep Gratings for InP/InGaAsP Optical Devices, Journal of Applied Physics 62 (8), October 15, 1987, pp. 3461-3463.	
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	CN	TANG, WILLIAM C., et al., Electrostatically Balanced Comb Drive for Controlled Levitation, Reprinted from Technical Digest IEEE Solid-State Sensor and Actuator Workshop, June 1990, pp. 198-202	
	CO	TORCHEUX, L. et al., Electrochemical Coupling Effects on the Corrosion of Silicon Samples in HF Solutions, J. Electrochem. Soc., Vol. 142, No. 6, June 1995, pp.2037-2046	
	CP	VAN KESSEL, PETER F. et al., A MEMS-Based Projection Display, Proceedings of the IEEE, Vol. 86, No. 8, August 1998, pp. 1687-1704	
	CQ	KELLER, CHRISTOPHER, Microfabricated Silicon High Aspect Ratio Flexures for In-Plane Motion, Dissertation submitted to University of California, Berkeley, Fall 1998	
AL	CR	MULLER, LILAC, Gimbaled Electrostatic Microactuators with Embedded Interconnects, Dissertation submitted to University of California, Berkeley, Spring 2000	

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Sheet 1 of 2

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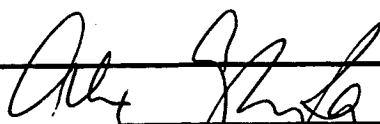
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 First Named Inventor Anderson, Robert L.  
 Art Unit 2835 2812  
 Examiner Name GHYKA  
 Attorney Docket Number 019930-003710US

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AC	AA	US-5,847,381	12-08-1998	T. Isogai	
AC	AB	US-6,747,340 B2	08-08-2004	S. Barnes, et al.	
	AC	US-			
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